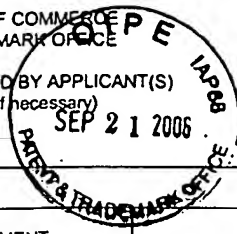



FORM PTO 1449 (modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)		ATTY DOCKET NO. 03500.017757.	APPLICATION NO. 10/535,196
<div style="text-align: center;">  </div>		APPLICANT HIDEYA KUMONI	
		FILING DATE May 18, 2005	GROUP 1765

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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

